

# Ryosuke Okuyama

## List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/2460103/publications.pdf>

Version: 2024-02-01

5  
papers

24  
citations

2258059

3  
h-index

2053705

5  
g-index

5  
all docs

5  
docs citations

5  
times ranked

12  
citing authors

#	ARTICLE	IF	CITATIONS
1	Hydrogen diffusion behavior in CH <sub>2</sub> P-molecular-ion-implanted silicon wafers for CMOS image sensors. <i>Materials Science in Semiconductor Processing</i> , 2022, 137, 106211.	4.0	1
2	Proximity gettering design of silicon wafers using silicon hydride and hydrocarbon mixture molecular ion implantation technique. <i>Materials Science in Semiconductor Processing</i> , 2021, 135, 106063.	4.0	3
3	Reduction of Dark Current in CMOS Image Sensor Pixels Using Hydrocarbon-Molecular-Ion-Implanted Double Epitaxial Si Wafers. <i>Sensors</i> , 2020, 20, 6620.	3.8	9
4	Molecular and Atomic Hydrogen Diffusion Behavior by Reaction Kinetic Analysis in Projection Range of Hydrocarbon Molecular Ion for CMOS Image Sensors. <i>Physica Status Solidi (A) Applications and Materials Science</i> , 2019, 216, 1900175.	1.8	5
5	Gettering Sinks for Metallic Impurities Formed by Carbon-Cluster Ion Implantation in Epitaxial Silicon Wafers for CMOS Image Sensor. <i>IEEE Journal of the Electron Devices Society</i> , 2018, 6, 1200-1206.	2.1	6